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Application No.	10/047,550	Prepared by	B2M	Tracking Number	05931458
Examiner-GAU	Fiorilla - 1731	Date	4-27-04	Week Date	04/05/04
		No. of queries	2		IFW

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|----------------------|------------------------|--------------------|----------------|
| a. Serial No. | f. Foreign Priority | k. Print Claim(s) | (p) PTO-1449 |
| b. Applicant(s) | g. Disclaimer | l. Print Fig. | q. PTOL-85b |
| c. Continuing Data | h. Microfiche Appendix | m. Searched Column | r. Abstract |
| d. PCT | i. Title | n. PTO-270/328 | s. Sheets/Figs |
| e. Domestic Priority | j. Claims Allowed | o. PTO-892 | t. Other |

- SPECIFICATION**
- a. Page Missing
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 - d. Other Missing Text
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 - f. Duplicate Text
 - g. Brief Description
 - h. Sequence Listing
 - i. Appendix
 - j. Amendments
 - k. Other

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FORM PTO-1449
(Modified)

JUL 14 2003

U.S. Department of Commerce
Patent and Trademark Office

Attorney Docket No.: SLM-06100

Serial No.: 10/047,550

INFORMATION DISCLOSURE STATEMENT BY APPLICANT
(Use Several Sheets If Necessary)

(37 CFR § 1.98(b))

Applicants: Gregory D. Miller et al

Filing Date: January 15, 2002

Group Art Unit: 2881

U.S. PATENT DOCUMENTS

Examiner Initials		Serial / Patent Number	Issue Date	Applicant / Patentee	Class	Subclass	Filing Date
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	AB	Des. 334,742	04/13/93	Hunter et al.	D14	113	10/03/90
	AC	Des. 337,320	07/13/93	Hunter et al.	D14	113	10/03/90
	AD	Re. 16,767	10/11/27	Jenkins			10/31/22
	AE	Re. 25,169	05/15/62	Glenn			06/01/54
	AF						RECEIVED JUL 14 2003 GROUP 1700
	AG						
	AH						
	AI						

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							Yes	No
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	AL	DE 197 23 618 A1	12/11/97	DE	G 03 F	1/14		X
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FORM PTO-1449 (Modified)	JUL 14 2003	U.S. Department of Commerce Patent and Trademark Office	Attorney Docket No.: SLM-06100	Serial No.: 10/047,550
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use Several Sheets If Necessary)			Applicants: Gregory D. Miller et al	
(37 CFR § 1.98(b))			Filing Date: January 15, 2002	Group Art Unit: 2381

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						Yes	No
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BJ	0 654 777 A1	05/24/95	EP	G09G	3/34		X
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	DQ	WO 01/006297 A3	01/25/01	WO	G02B	27/10		X
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		Document Number	Publication Date	Country / Patent Office	Class	Subclass	Translation	
							Yes	No
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Patent and Trademark Office

Attorney Docket No.: SLM-06100

Serial No.: 10/041450

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(37 CFR § 1.98(b))

Applicants: Gregory D. Miller et al

Filing Date: January 15, 2002

Group Art Unit: 288

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Examiner:

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U.S. Department
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Attorney Docket No.: SLM-06100

Serial No.: 10/047,550

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Applicants: Gregory D. Miller et al

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		Filing Date: January 15, 2002	Group Art Unit: 2881	

OTHER DOCUMENTS (Including Author, Title, Date, Relevant Pages, Place of Publication)

GY	R. W. Corrigan et al. "Calibration of a Scanned Linear Grating Light-Valve, Projection System for E-Cinema Applications", Silicon Light Machines, SID '99, San Jose, CA, 27 pgs, 1999.
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